



501.37892X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Yoko IKEDA *et al.*

Serial No.: 09/452,149

Filed: 1 December 1999

For: INSPECTING METHOD, INSPECTING SYSTEM, AND
METHOD FOR MANUFACTURING ELECTRONIC DEVICES

Art Unit: 2623

Examiner: Virginia M. Kibler

2623
#9/B
1-1903

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Technology Center 2600

AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231

13 January 2003

Sir:

In response to the Office Action mailed 12 September 2002 in connection with the above-identified application, Applicant respectfully submits the following amendments and remarks.

IN THE SPECIFICATION:

Please make the following corrections in the Substitute Specification filed by Applicant in the present case on 9 June 2000.

Please delete the paragraph on page 1, lines 6-17, and enter the following replacement paragraph therefor.

The present invention relates to an analyzing unit, an inspecting system and a manufacturing method using the inspecting system, which are applied to a production line used in the manufacture of electronic devices and the like; and, more

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